



# COST

European Network on New Sensing Technologies for Air Pollution Control  
and Environmental Sustainability - *EuNetAir*

COST Action TD1105

**WGs and MC Meeting at Cambridge, 18-20 December 2013**

**AFFORDABLE NANOSENSORS FOR ENVIRONMENTAL  
MONITORING**



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WG1 Member

**University Rovira i Virgili / Spain**

 **cost**  
EUROPEAN COOPERATION IN SCIENCE AND TECHNOLOGY



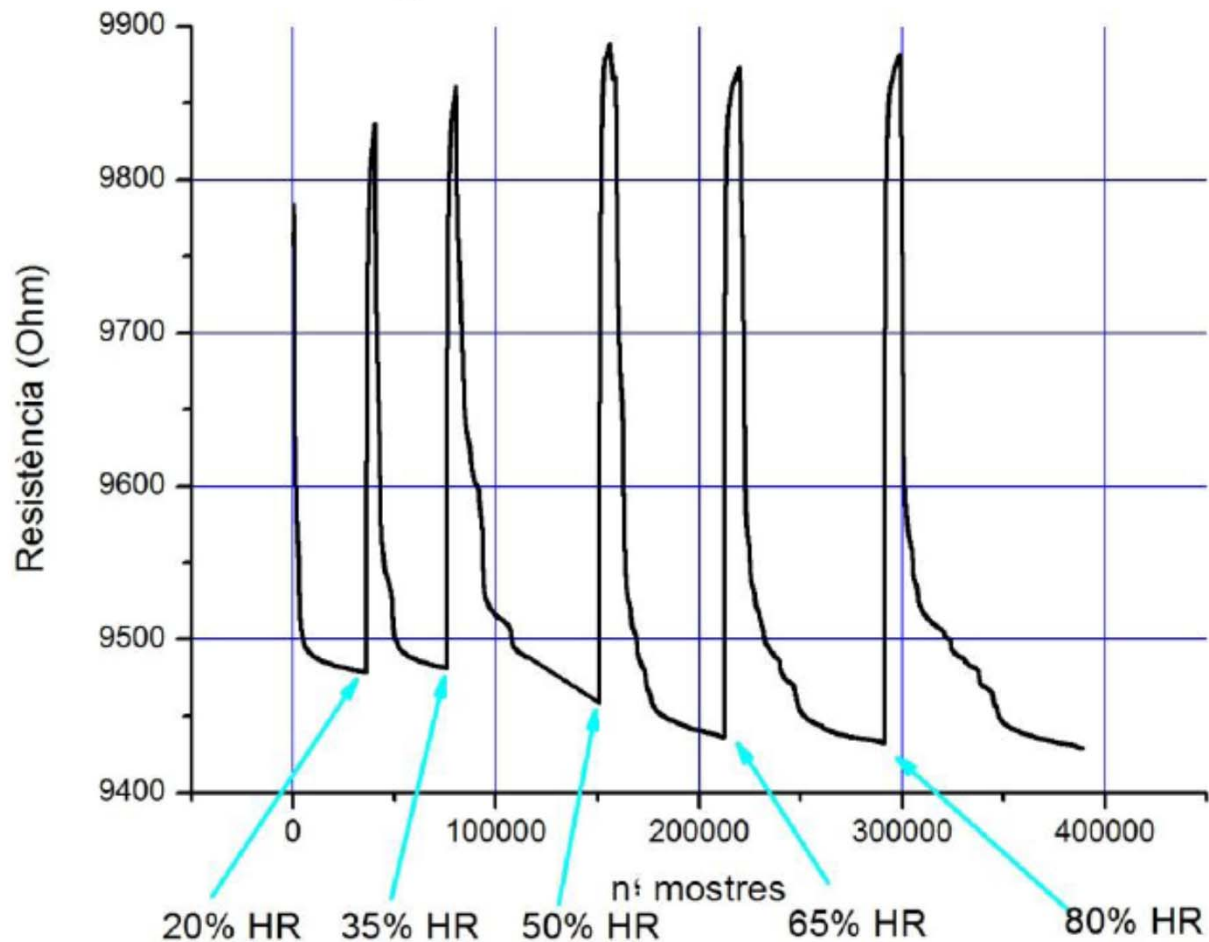
# AFFORDABLE NANOSENSORS FOR ENVIRONMENTAL MONITORING

This talk reviews the research activities of the URV group and comprises:

- Carbon black sensors
- Resistive carbon nanotubes sensors
- Resistive low-dimensional metal oxide sensors
- Flexible substrate sensors
- Resonant sensors functionalised with carbon nanotubes or zeolites

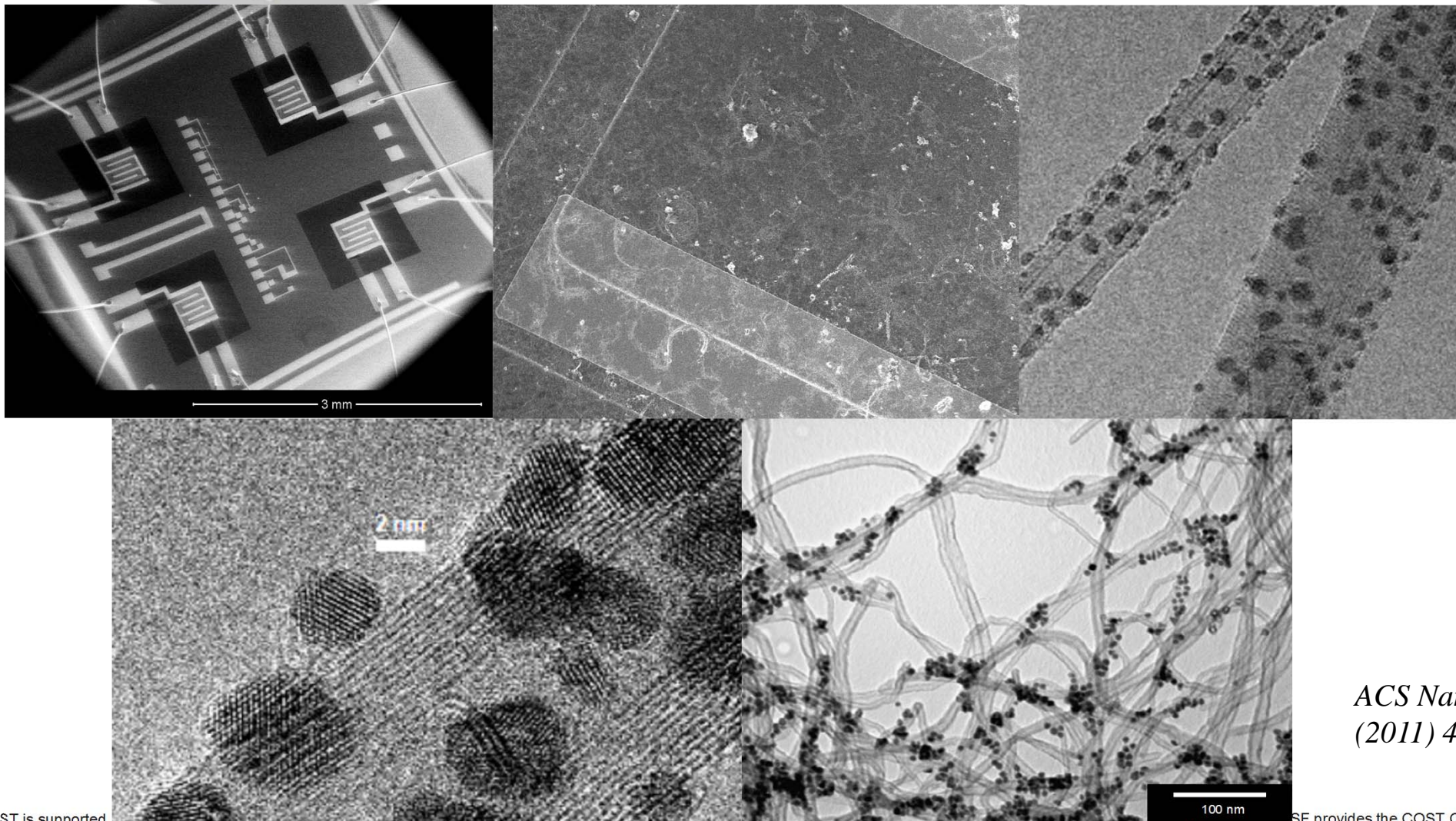
# Micro/nano gas sensors using carbon black

- Humidity sensors based on carbon black nanoparticles



# Micro/nano gas sensors using MWCNTs

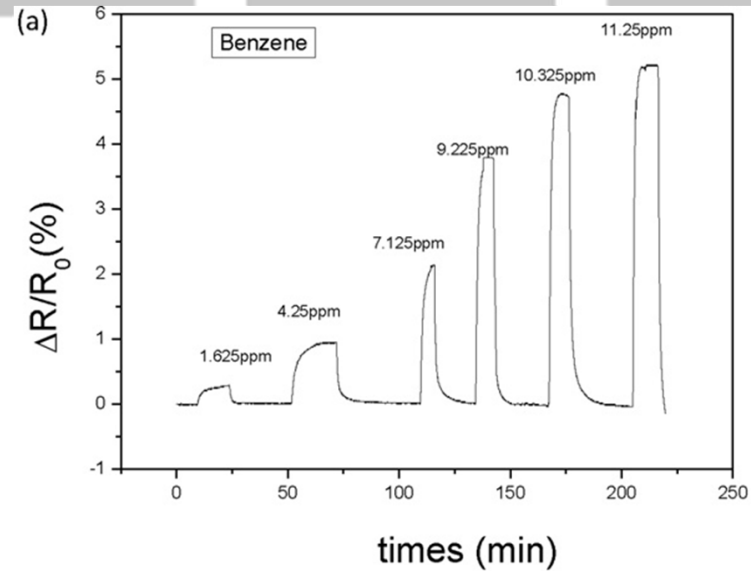
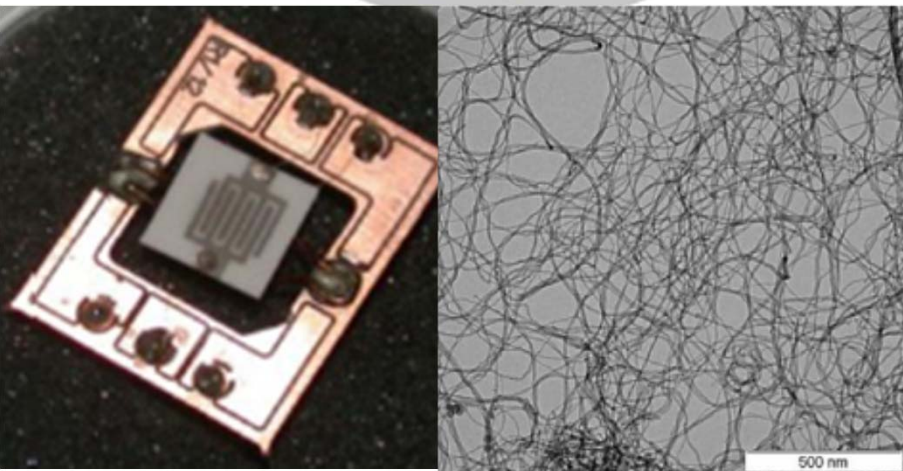
- Gas sensors based on plasma-treated, metal-decorated MWCNTs and graphene



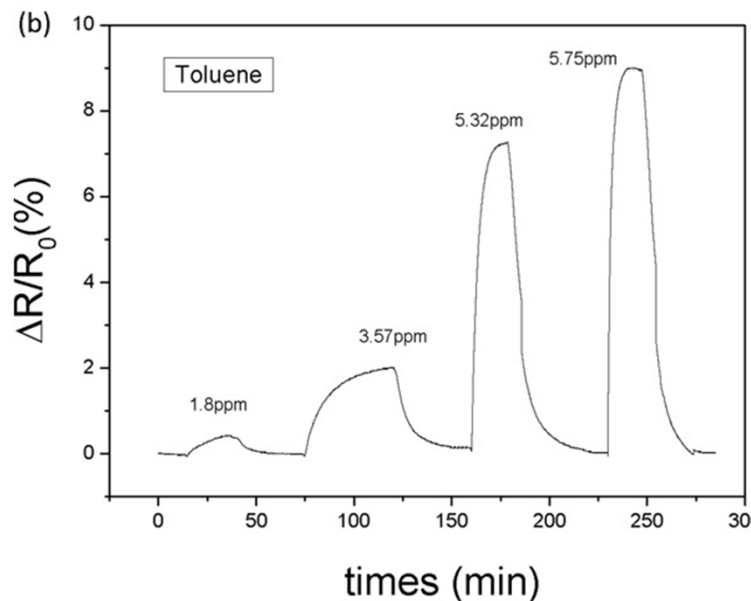
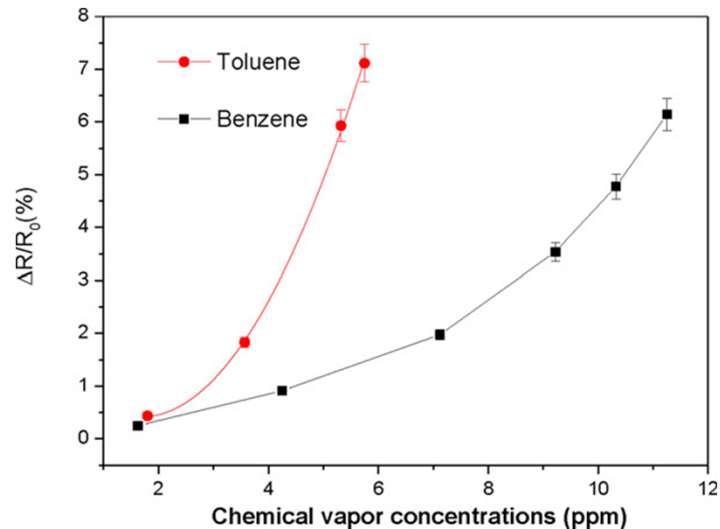
*ACS Nano, 5  
(2011) 4592*

# Micro/nano gas sensors using MWCNTs

- Gas sensors based on plasma-treated, metal-decorated MWCNTs and graphene



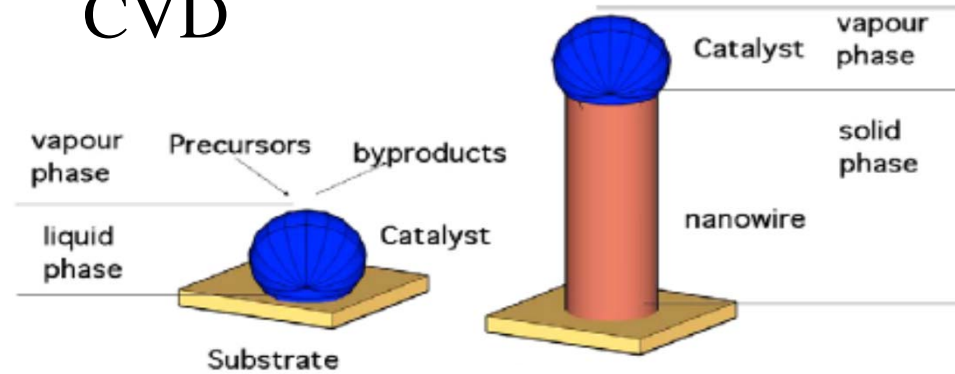
**Room temp.**



*Sensors and Actuators B 182 (2013) 344–350*

# MOX NW sensors VLS (catalyzed)

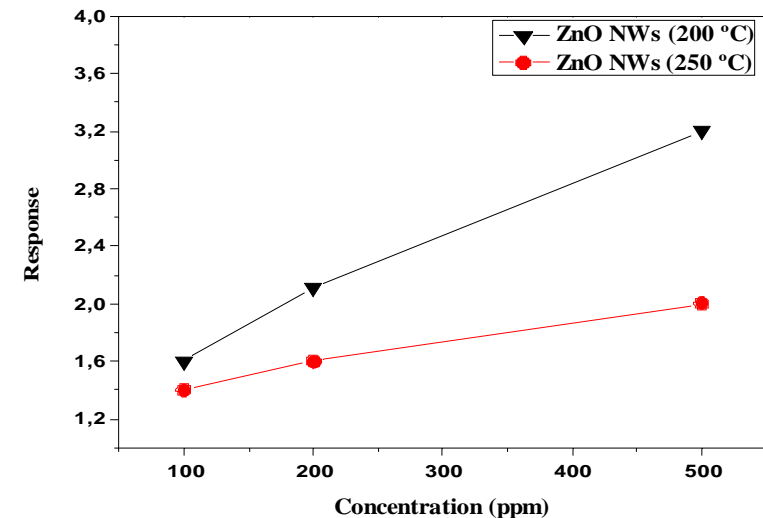
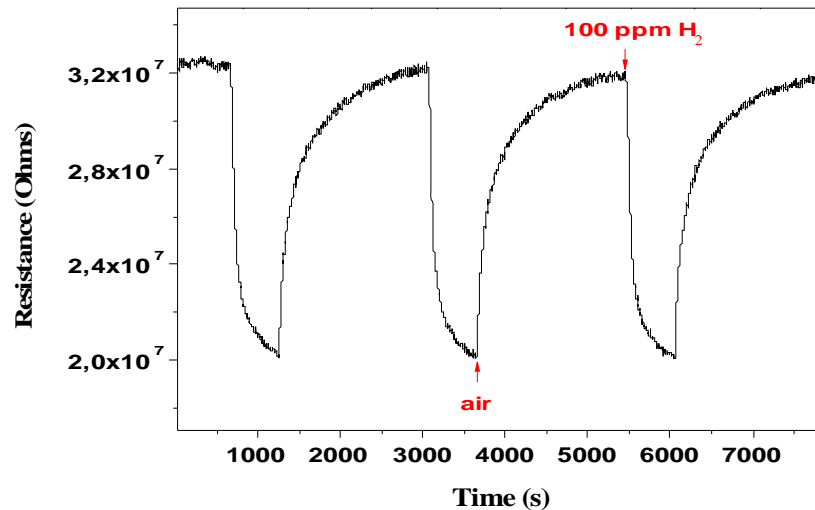
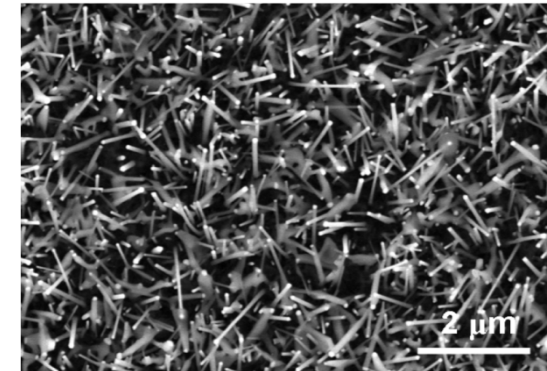
## CVD



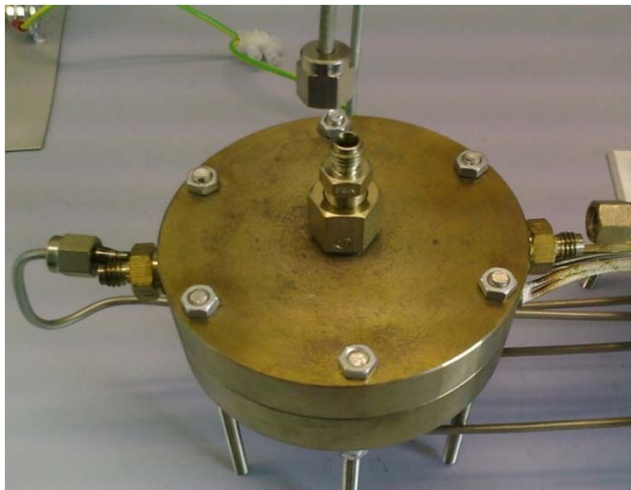
ZnO grown by CVD (900°C) on SiO<sub>2</sub> substrates using Au NP as catalyst.

Substrate conditioning: Au NP prepared by sputtering + annealing.

*IMCS 2014*



# MOX NW Sensors: Aerosol-Assisted CVD (VS)

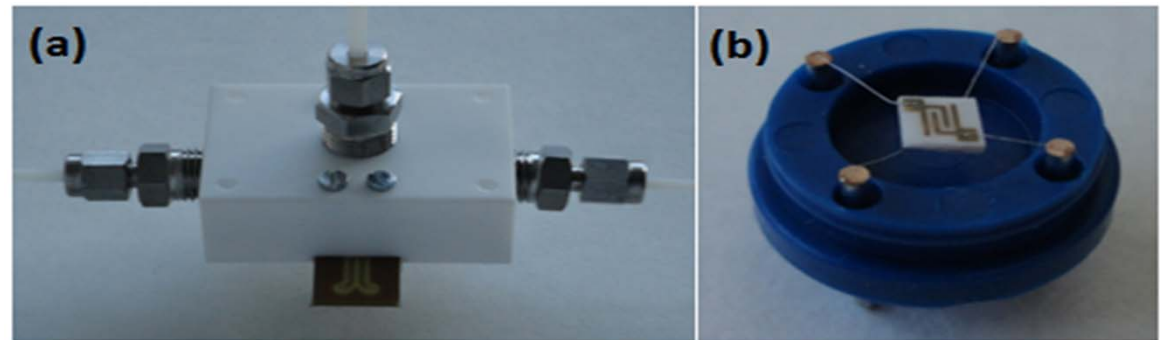


Hot wall AACVD reactor

**Deposition time: 45-60 min**

**Precursor : 150 mg**

**T °C used : up to 500 °C**



(a) AACVD cold wall reactor, (b) Alumina gas sensor

**Deposition time: 15-20 min**

**Precursor : 50 mg**

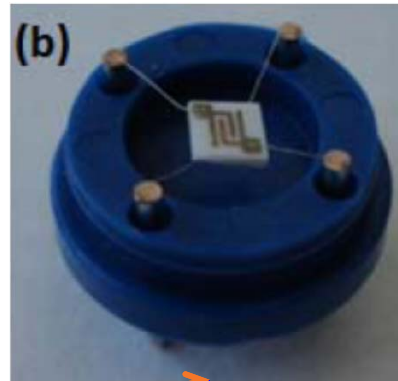
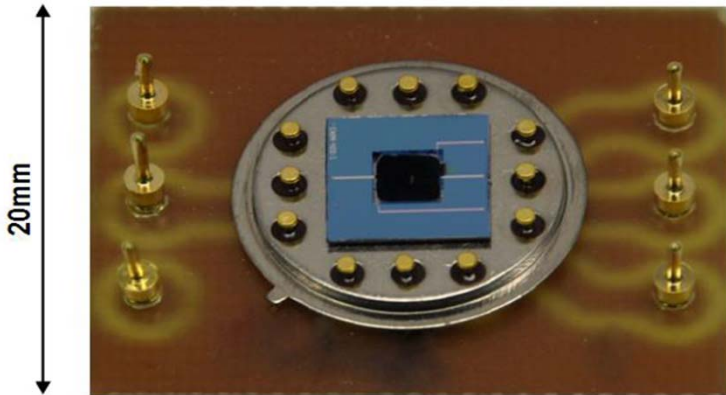
**T °C used : up to 600°C**

**Doped nanowires growth in a single step**

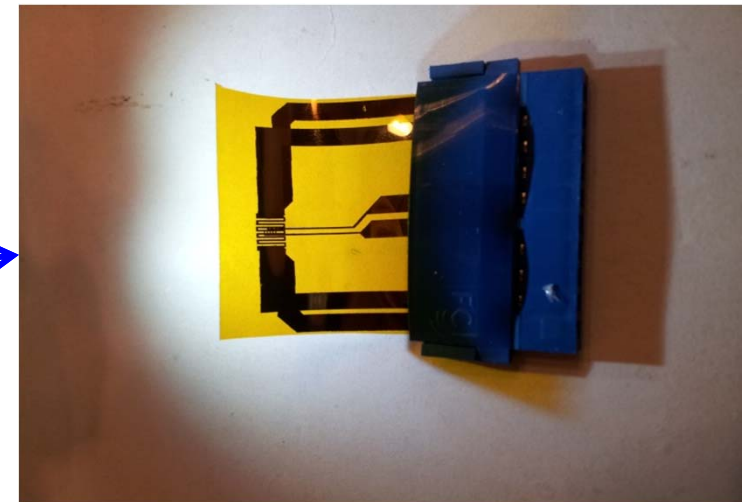
# MOX NW Sensors: Aerosol-Assisted CVD (VS)



25mm

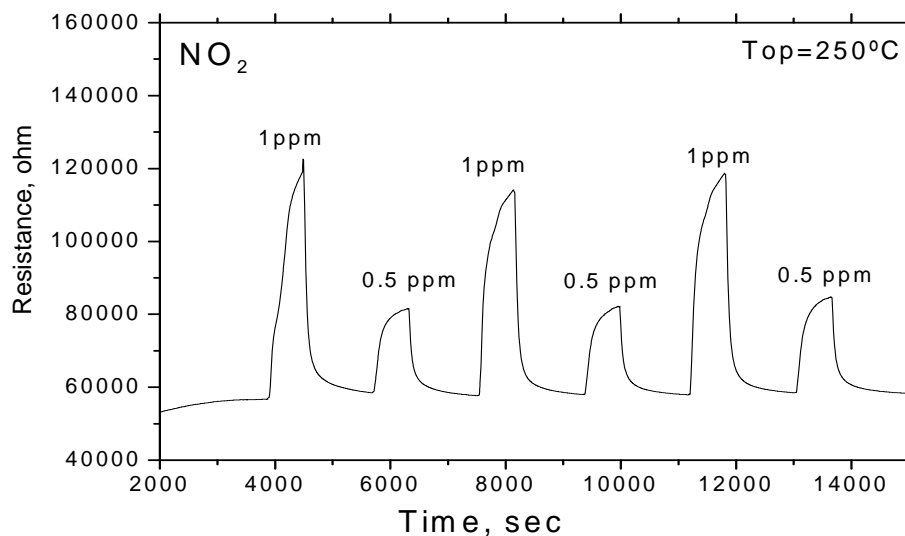
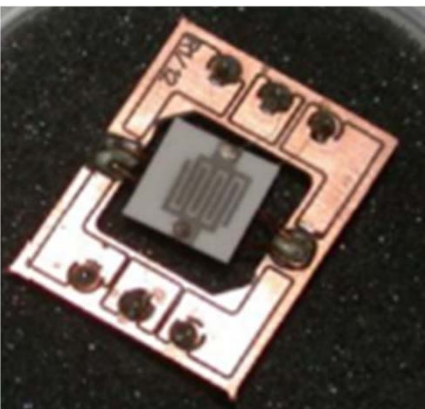


Direct growth of  
NWs on ceramic,  
micromachined  
silicon and flexible  
substrates

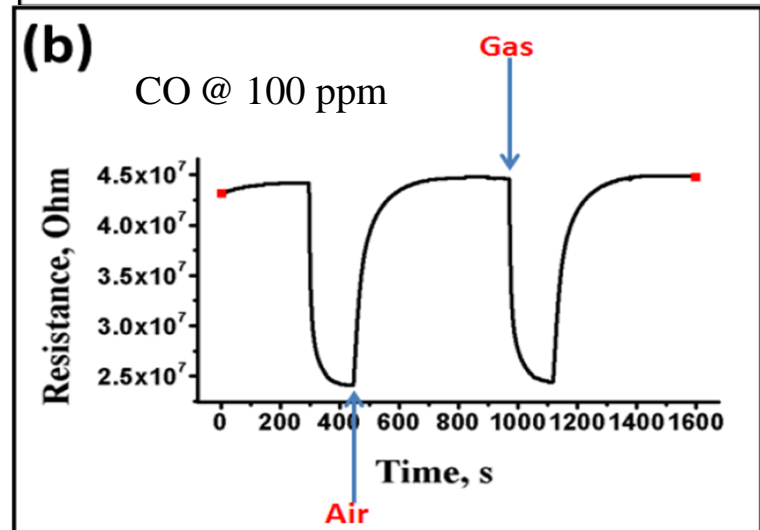
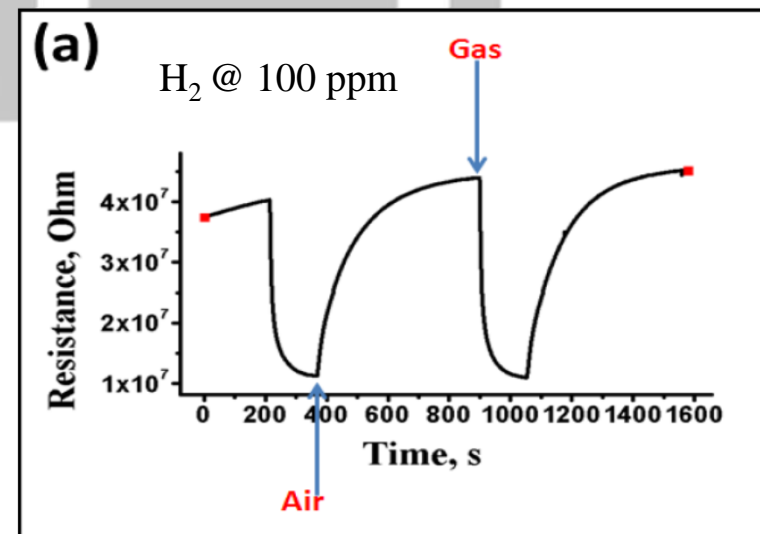




# MOX NW Sensors: Aerosol-Assisted CVD (VS)



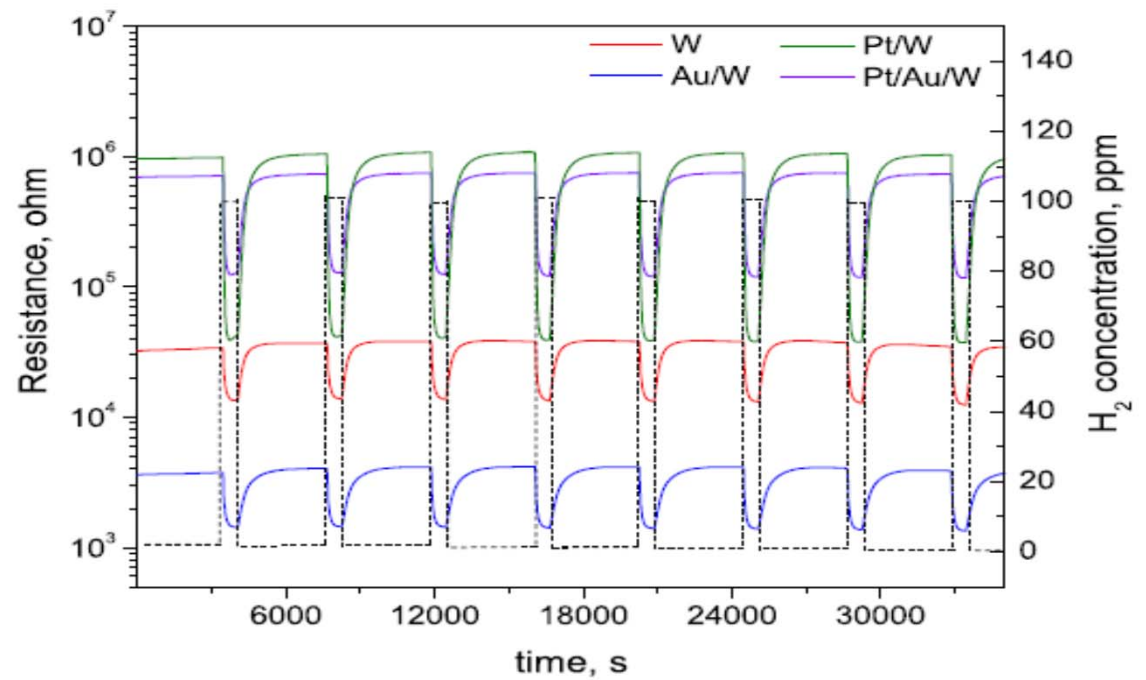
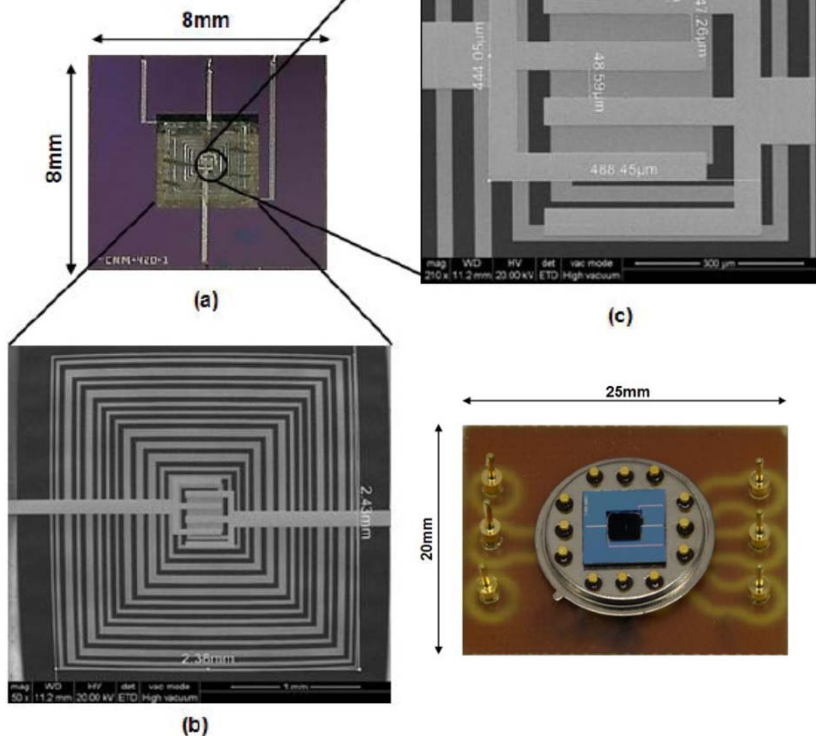
Au-WO<sub>3</sub> NWs



Pt-WO<sub>3</sub> NWs, operated at 250°C

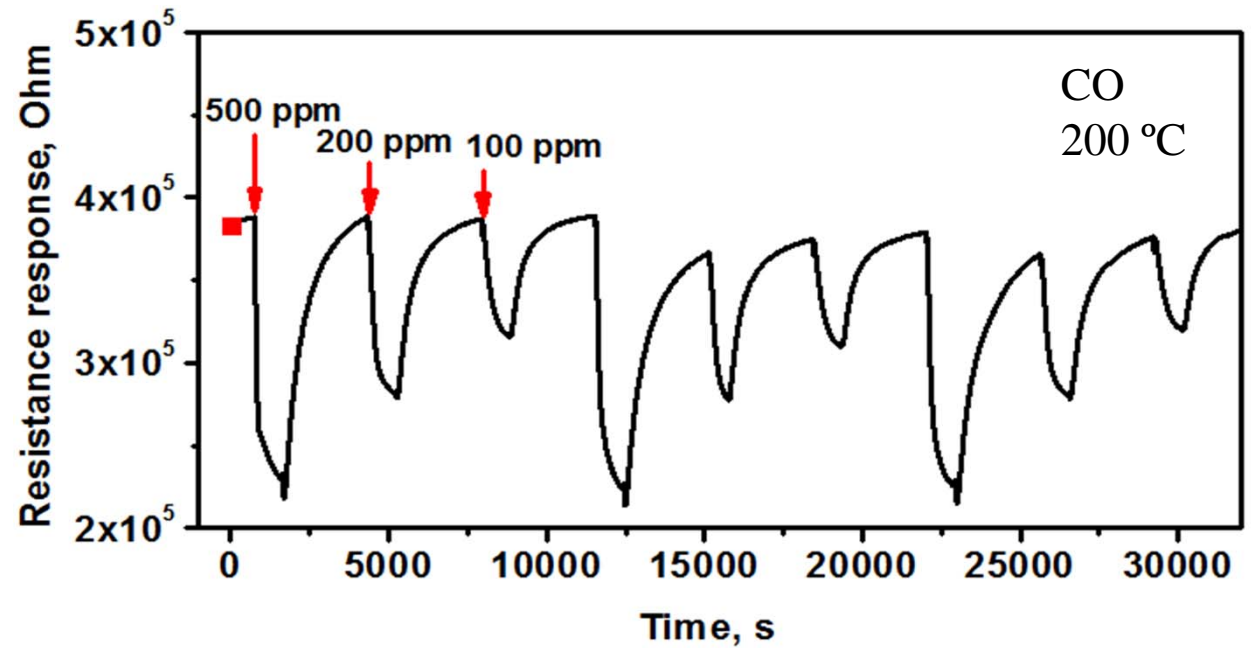
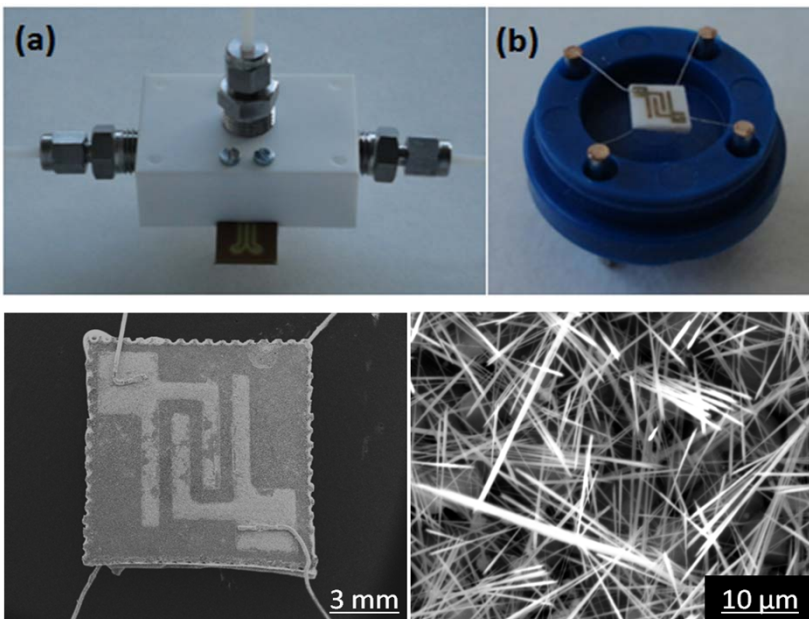
*Sensors and Actuators B* 161 (2012) 406  
*Int. J. Nanotechnology*, 10(2013) 455-469  
*Thin Solid Films*, 548 (2013) 703-709

# MOX NW Sensors: Aerosol-Assisted CVD (VS)

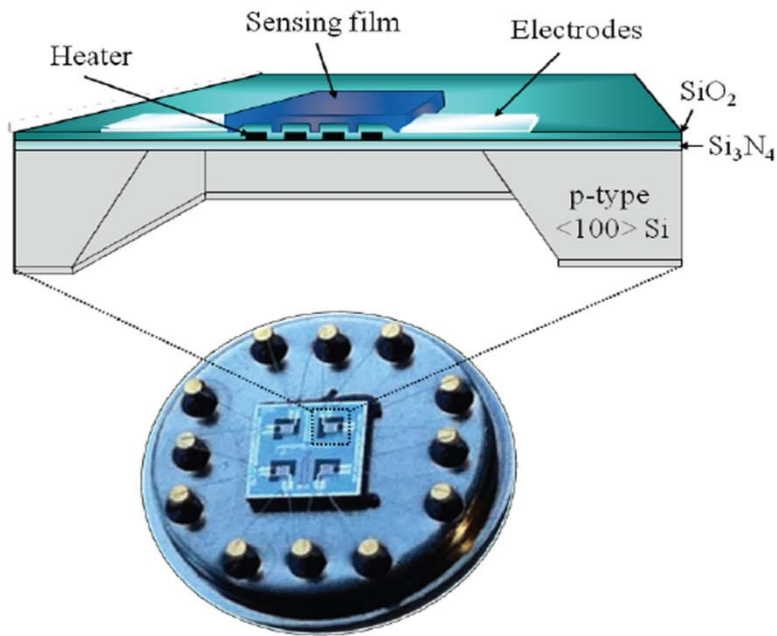
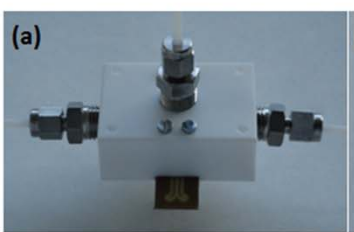


Film resistance changes towards hydrogen 100 ppm at 250 °C.

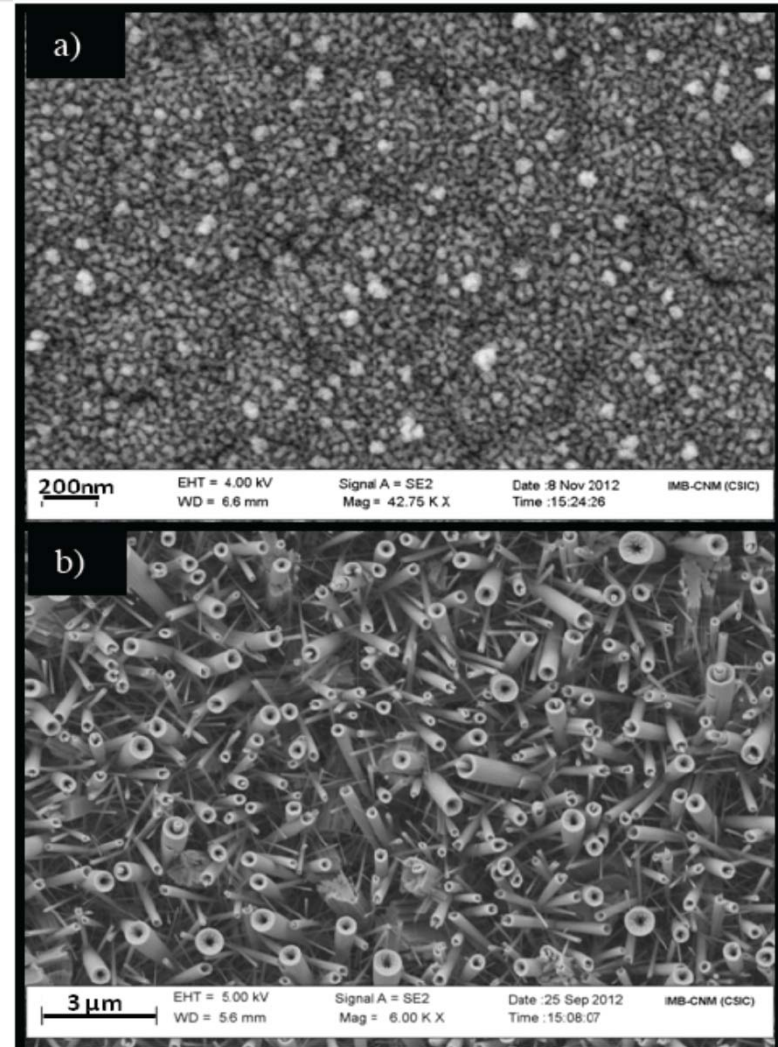
# MOX NW Sensors: Aerosol-Assisted CVD (VS)



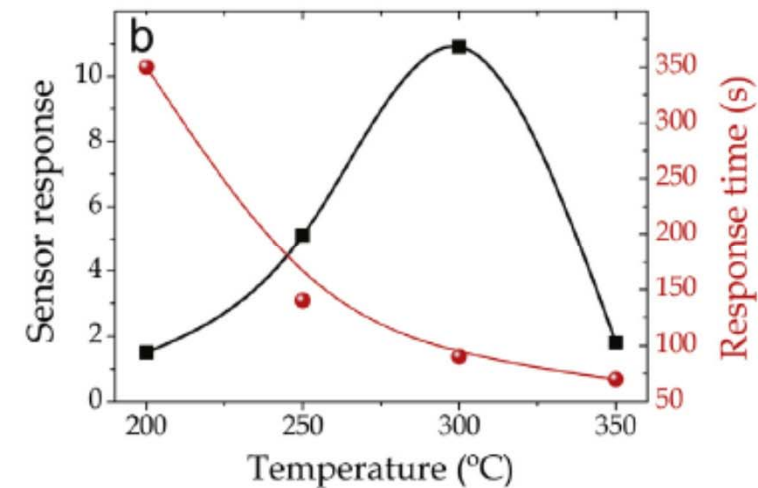
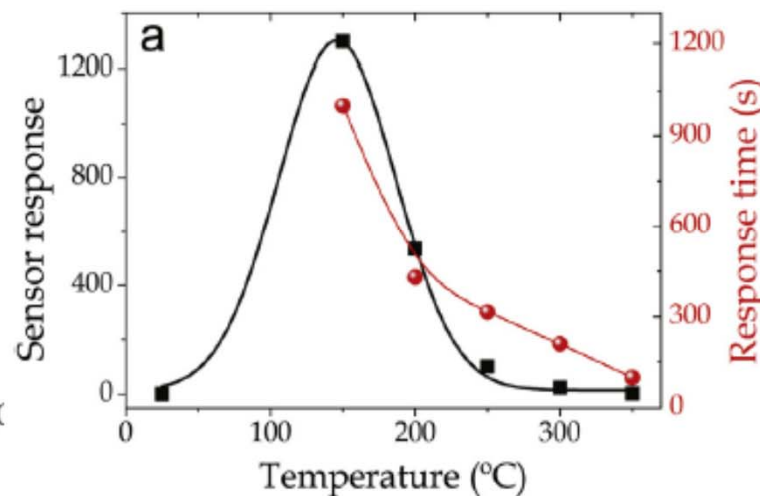
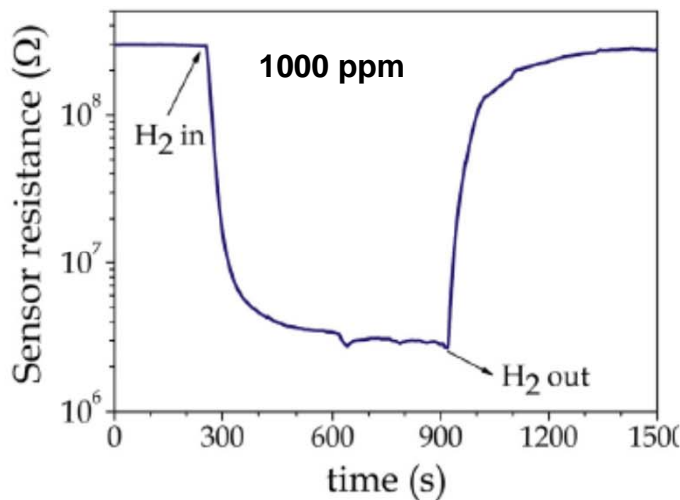
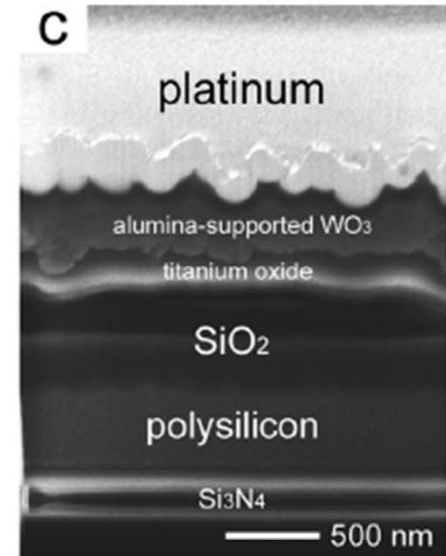
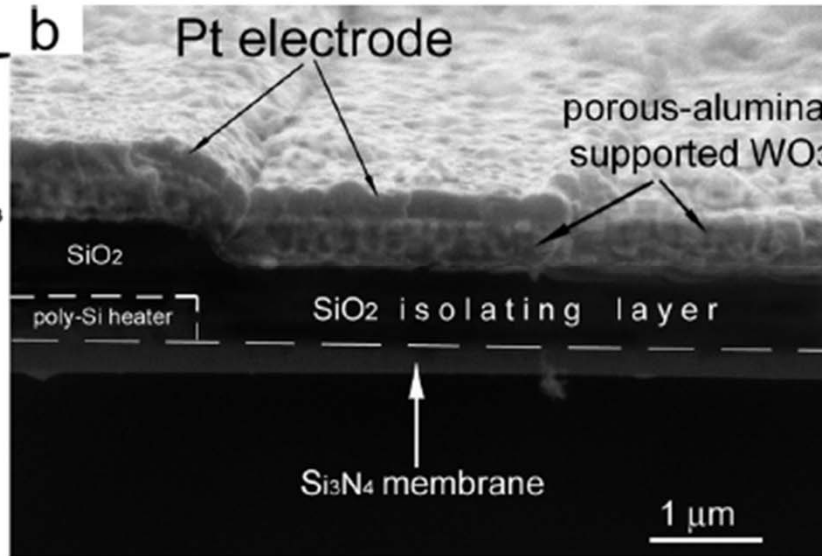
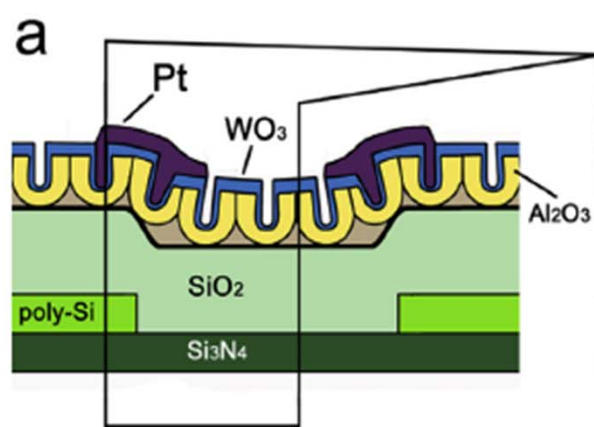
# MOX NW Sensors: Aerosol-Assisted CVD (VS)



Direct growth of nanomaterials onto micro-hotplate transducers using the integrated heating element to reach and keep reaction temperature during growth.

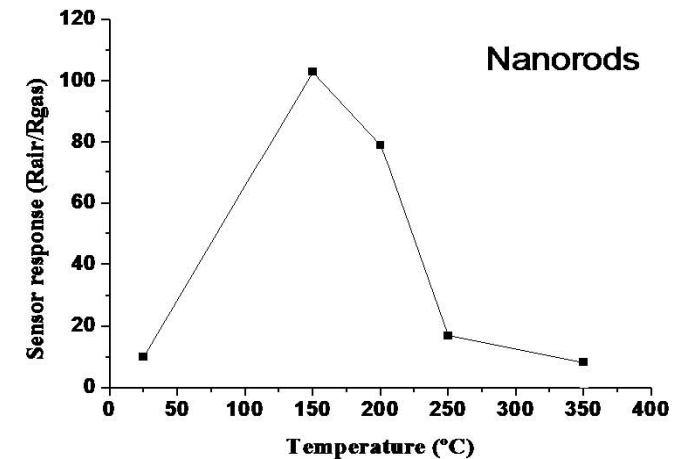
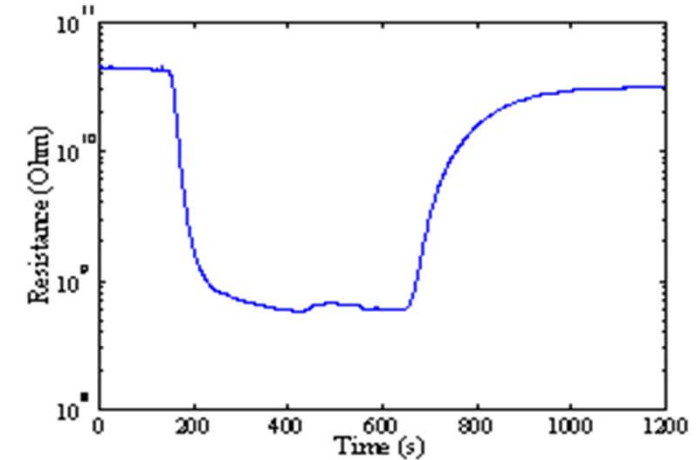
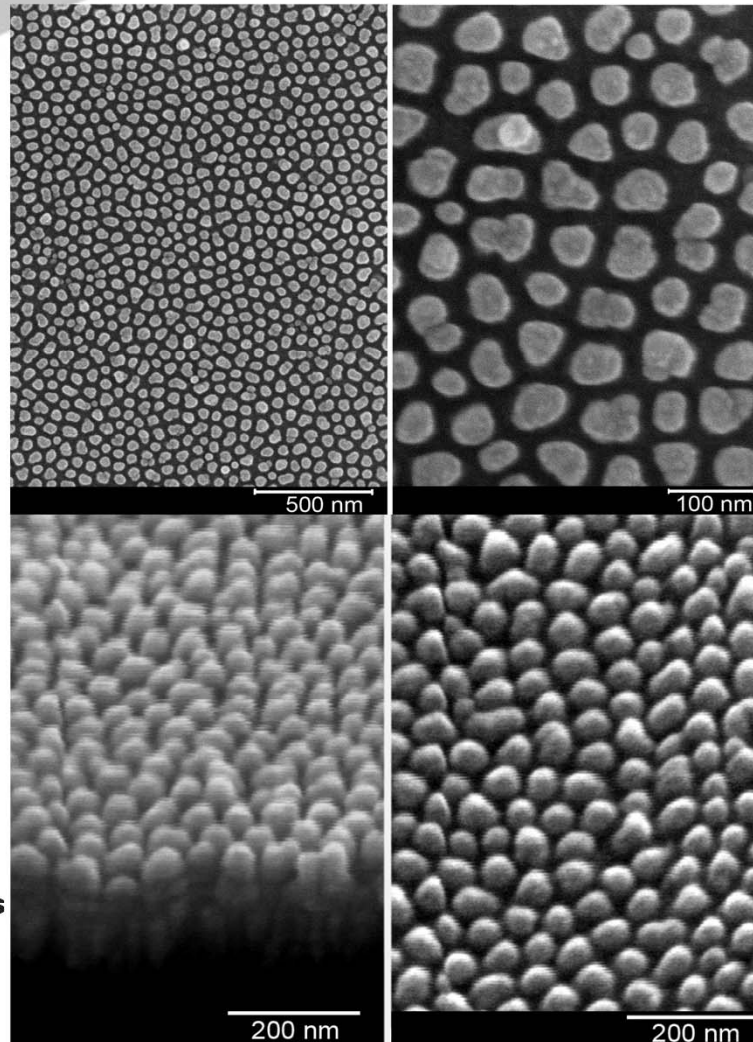
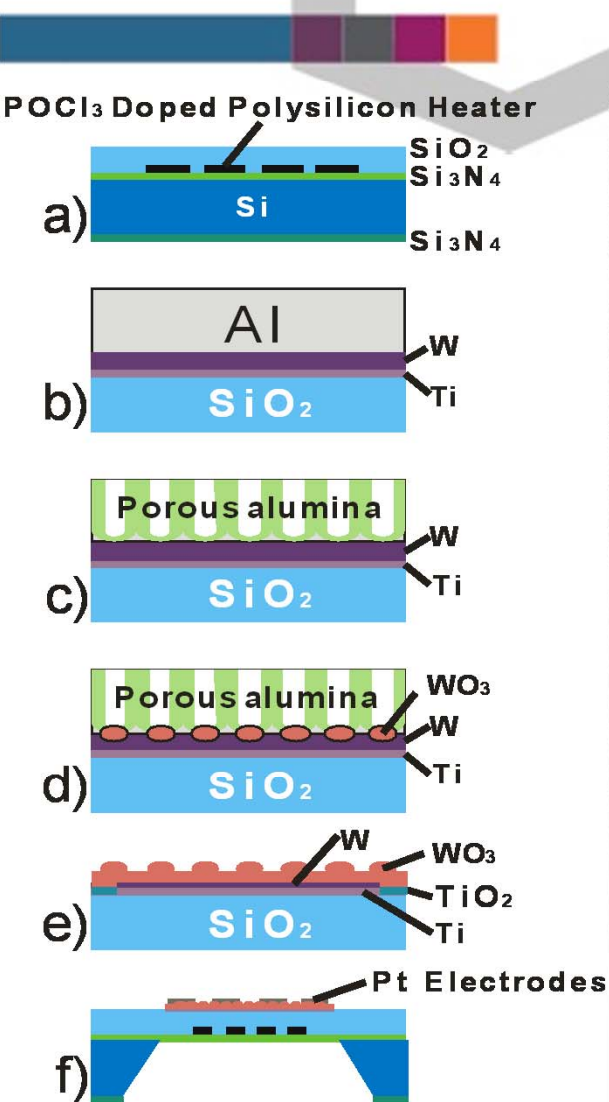


# MOX nanotubes by smart anodization

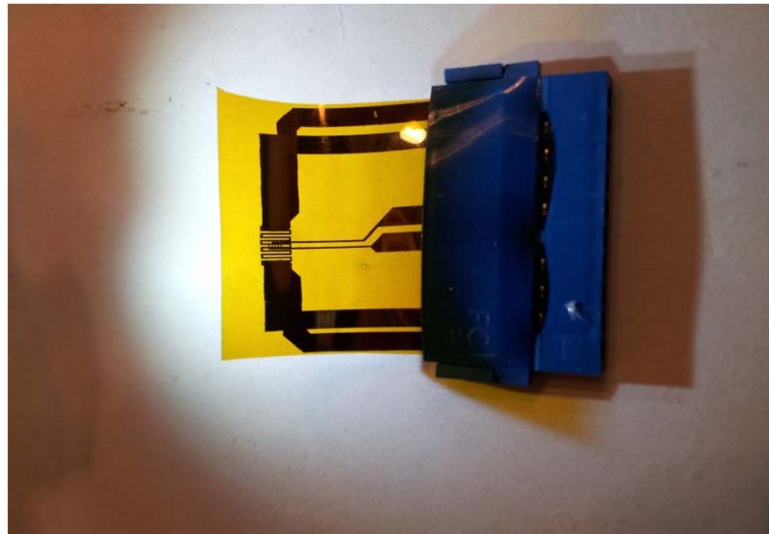
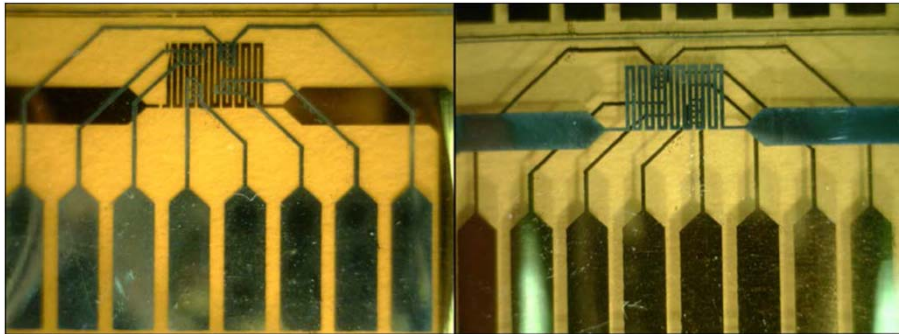


# MOX nanorods by smart anodization

- Gas microsensors based on smart anodisation (tungsten oxide, titania or niobia)

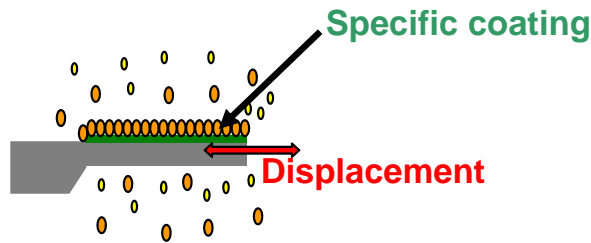
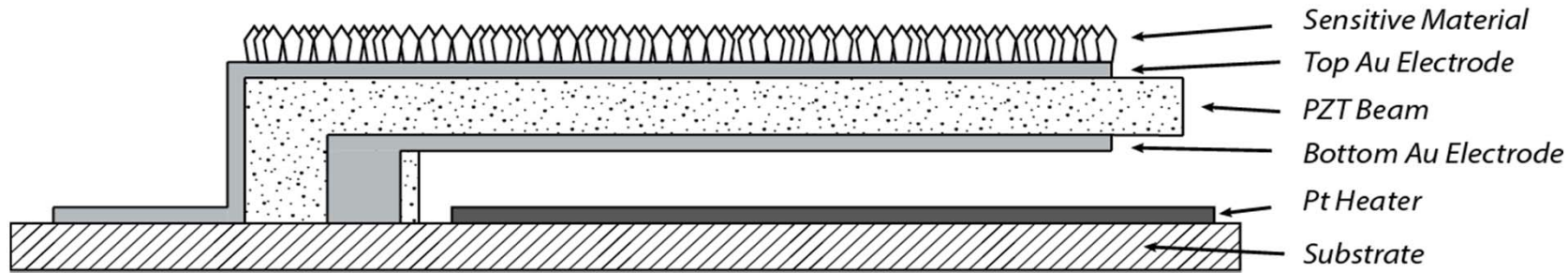
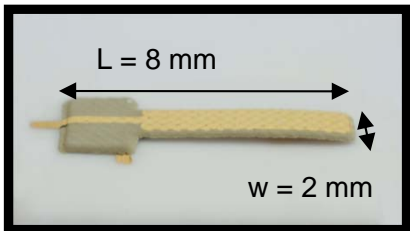
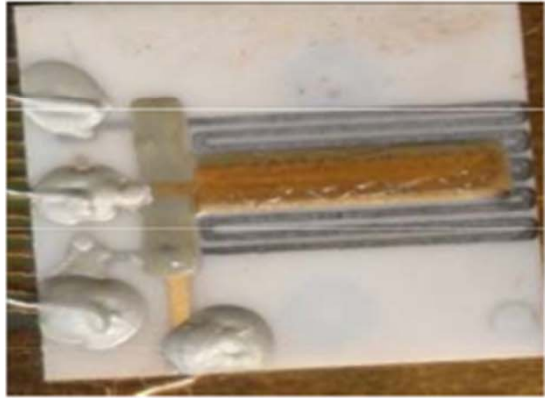


# Nanomaterials on flexible substrates: sensors on fabrics



# Screen-printed resonant sensors using CNTs and zeolites

PZT cantilever



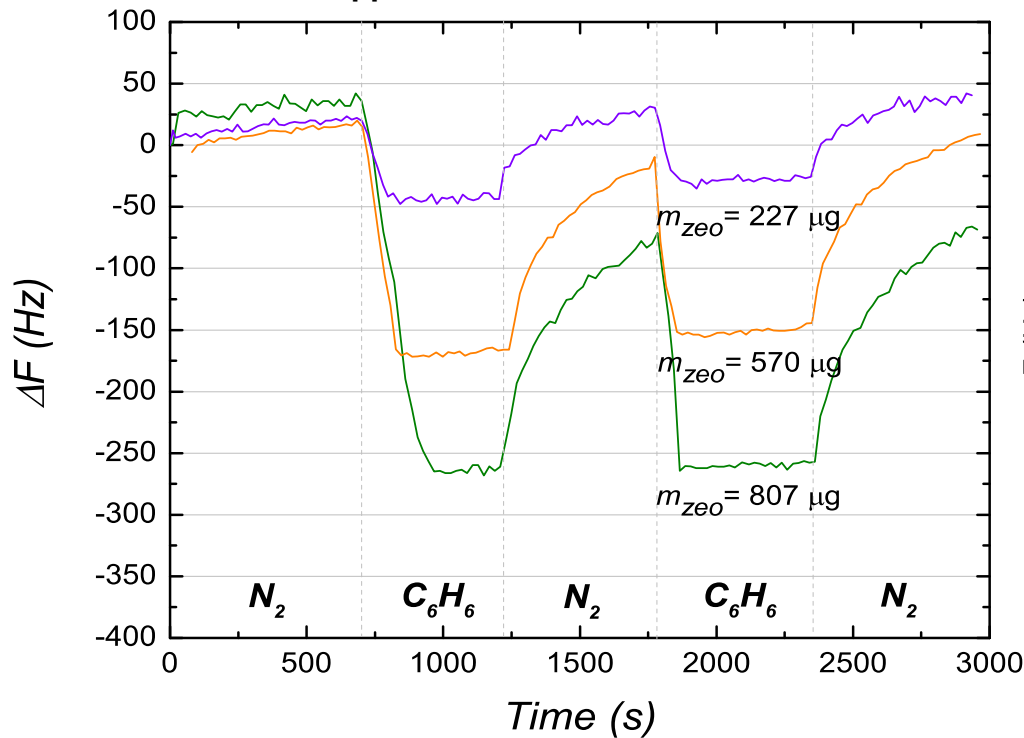
Surface functionalisation with CNTs /zeolites

Resonant frequency maximum at 65-70 kHz

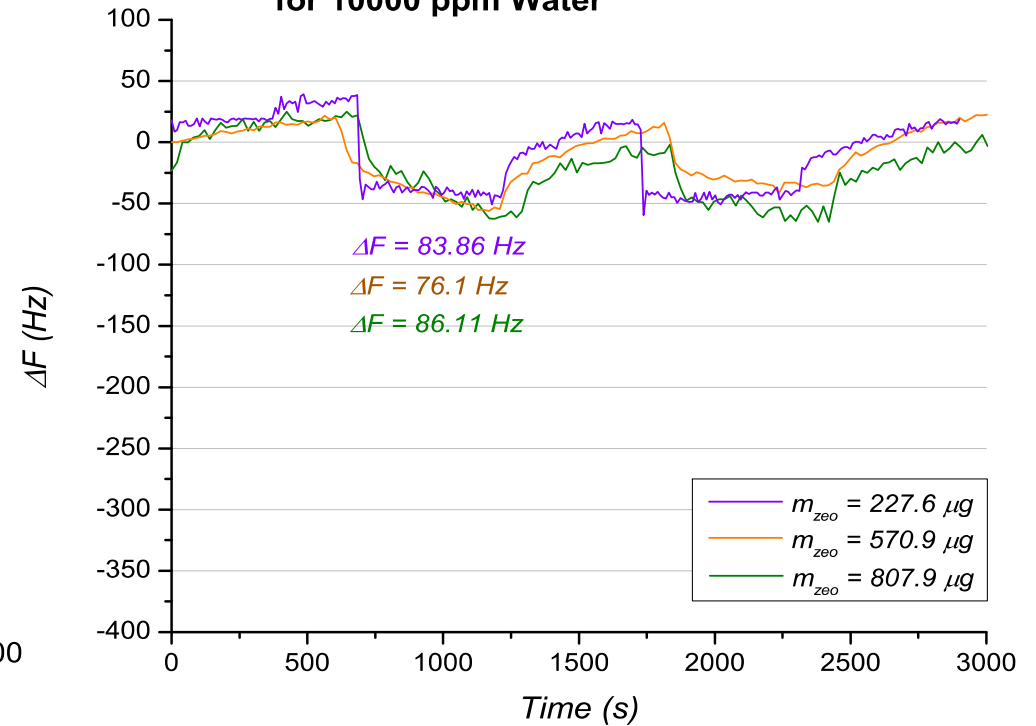


# Screen-painted resonant sensors using CNTs and zeolites

Frequency shift regarding zeolite's mass for 1000 ppm Benzene



Frequency shift regarding zeolite's mass for 10000 ppm Water



# Conclusions

COST

- AA-CVD leads to highly stable low-dimensional MOX sensors (drift below 8% in 12 months)
- Resistive CNT sensors show *ppb* LOD for aromatics
- Smart anodization techniques are compatible with MEMs for the integration of MOX nanotubes and nanorods
- MOX and CNTs can *easily* be integrated in flexible substrates
- Our resonant sensors still less sensitive than our resistive sensors